

ABSTRACT OF THE DISCLOSURE

A gas purifying system for purifying an object gas includes a gas flow line through which the object gas to be purified flows from an object gas generation mechanism, a
5 discharge reaction device provided on a way of the gas flow line, a filter member disposed in the discharge reaction device having a structure capable of trapping particular matter contained in the object gas during a time when the object gas passes through the filter member; and a discharge generation
10 device operatively connected to the discharge reaction device for causing electric field inside the discharge reaction device and generating discharge plasma therein.